

Notice of References Cited	Application/Control No. 09/737,638		Applicant(s)/Patent Under Reexamination JOHNSON, F. SCOTT	
	Examiner Nathan W. Ha		Art Unit 2814	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-4,839,305	06-1989	Brighton, Jeffrey E.	257/518
	B	US-6,211,562	04-2001	Forbes et al.	257/581
	C	US-4,534,806	08-1985	Magdo, Ingrid E.	257/51
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Fred Walczyk et al., Tailoring Interfacial Oxide for Polysilicon Bit-Cell Contacts and Emitters with In Situ Vapor HF Interface Cleaning and Polysilicon Deposition in a 4Mbit BiMOS Fast Static RAM, 1992, IEEE, Volume 4.2, pp. 84-87.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.